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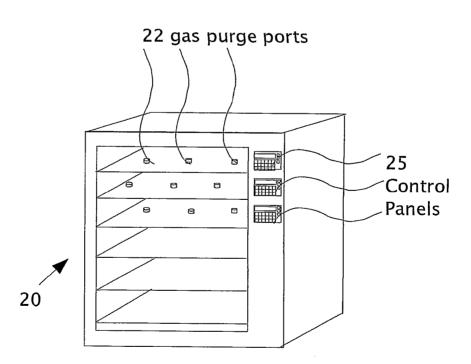
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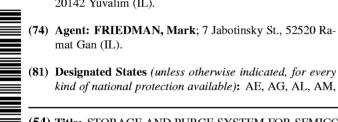
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(54) Title: STORAGE AND PURGE SYSTEM FOR SEMICONDUCTOR WAFERS



(57) Abstract: A system for storage and maintenance of semiconductor wafers or reticles under fabrication between process steps of the fabrication. The system is configured as either a stocker, an overhead transport system (OHT) or an overhead buffer (OHB with gas-purge ports which mechanically mate with a standard receptacle of a wafer/reticle carrier. A control circuit is attached to the gas-purge ports which controls gas flow into the carrier through gas purge port said Control is performed even in the absence of a communications network attached to the control circuit.





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International application No.

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Minimum documentation searched (classification system followed by classification symbols)			
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Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched			
Electronic data base consulted during the international search (name of data base and, where practicable, search terms used)			
C. DOCUMENTS CONSIDERED TO BE RELEVANT			
Category *	Citation of document, with indication, where ap	propriate, of the relevant passages	Relevant to claim No.
x, y	US 6,634,845 (KOMINO et al.) 21 October 2003 (21.	08.2003), columns 15, 16.	1, 6, 12, 18, 20
y, e	US 2007/0187272 (BONESS et al) 16 August 2007 (16.08.2007), page 4, paragraph 58.		7, 9,
у	US 2001/0028456 (NISHI) 11 October 2001 (11.10.2001), page 15, paragraph 192. 10, 11, 12, 13, 14, 13, 14, 15, 21,22		10, 11, 12, 13, 14, 15, 16, 21,22
у	US 7,094,291 (REARDON et al) 22 August 2006 (22.08.2006), figure 1 2, 3, 4, 5,		
у .	US 2005/0260333 (MIYATA) 24 November 2005 (24.11.2005), page 8, paragraph 110		
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